

In_{0.53}Ga_{0.47}As (lattice-matched on InP) epi wafer specification

Specifications

- Dimensions: Available in 2, 3, and 4 inch sizes.
- Materials: InP, InGaAs, InAlAs, InGaAsP.
- Products: Primarily for photodetector devices.
- **Production Method:** Through MOCVD.
- Applications: Telecommunications, Industrial, Medical, Laser diodes, among various others.

Features and Performance

- Layer Background Concentration: Features typical i-layer background concentration below 5e14, verified by Hall measurements.
- Diode Fabrication: Offers quick-lot diode fabrication with characterization data readily available.
- Current Characteristics: Exhibits low dark current and typical leakage currents below 1nA at -5 volts.

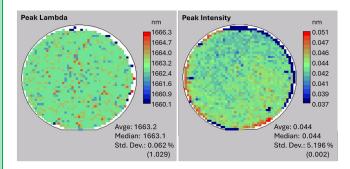
Performance

- Importance of Performance: While performance is crucial for engineers, true success in wafers also demands volume and consistency. EPI Solution™ InGaAs photodetector wafers excel in all three areas by combining high performance with rapid lot data, ensuring superior yield and quality.
- Manufacturing Excellence: Our InGaAs wafers, produced using MOCVD, exceed industry standards. This enables the integration of next-generation technology into your applications.

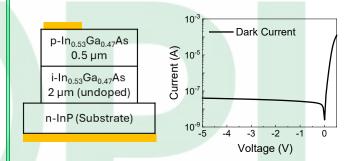
Empowering Your Technological Advancements

- Advancing Technology: Adopting cutting-edge technology doesn't have to be complicated, and you don't need to navigate it alone. EPI solution offers InGaAs capabilities for advanced photodetector designs and boasts state-of-theart 4 inch capacity to meet your specific requirements.
- Our Expertise: With extensive knowledge in both materials and devices, we provide high-quality, high-yield products along with the advanced technology necessary for your needs.

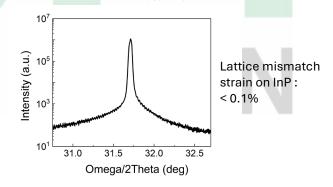
PL map of 2 inch In_{0.53}Ga_{0.47}As epi wafer



I-V characteristics of In_{0.53}Ga_{0.47}As epi structure



XRD spectrum of In_{0.53}Ga_{0.47}As on InP substrate



Characterization of In_{0.53}Ga_{0.47}As layer

Evaluation Items	Unit
Background carrier concentration	< 8x10 ¹⁴ cm ⁻³
Background carrier mobility	> 8,500 cm²/Vs
Thickness variation within wafer	< 10 %